



Techniques and Instrumentation at the Materials Research Lab Central Research Facilities



Kathy Walsh, Senior Research Scientist
(with many contributions from the rest of the MRL staff)

Illinois Materials Research Lab

- ~ 50,000 sq.ft. labs
- ~ 150 tools
- 24 technical staff members
- User facility

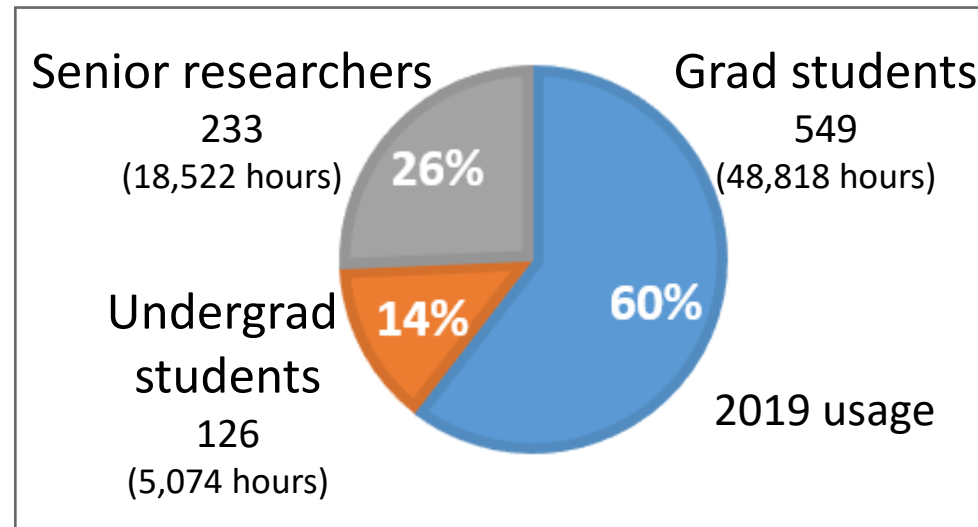


(next door to Loomis)

Tours and general questions:
mrl-facilities@illinois.edu

Illinois Materials Research Lab

- Open 24/7 to researchers at all levels
- Academic, government, and industrial

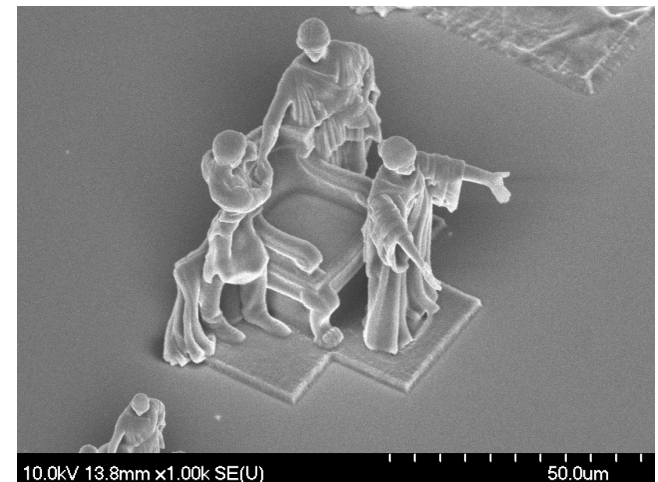


Submit proposal → be trained → do science
go.illinois.edu/MRLorientation

Tours and general questions:
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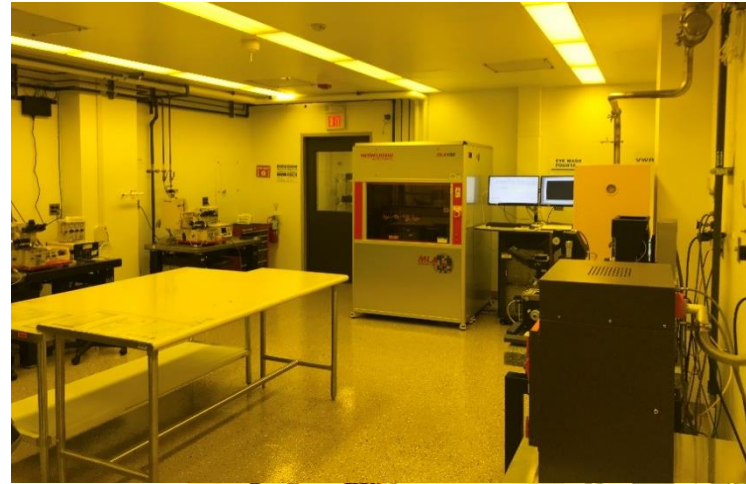
Materials Research

- Fabrication
 - Microfabrication (cleanroom lithography)
 - Nanoscale 3D printing
- Characterization
 - Atomic scale to centimeter scale
 - Morphology of samples
 - Composition of samples
 - Behavior of samples



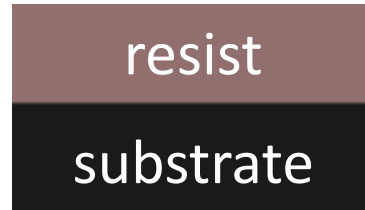
Microfabrication

- Often used for devices
- Cleanroom (not dusty)
- Deposit light- or electron-sensitive resist
- Expose and develop pattern
 - UV light
 - electrons (smaller)
- Deposit material
- Remove resist
- Alternatively, etch away material



Lithography

1. Deposit resist



2. Expose a pattern; develop (remove) resist



3. Deposit material (gold, etc.)



4. Liftoff (remove remaining resist)

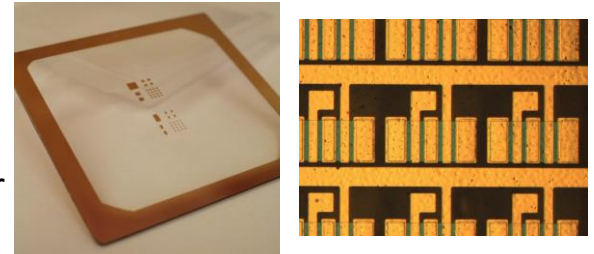


Lithography

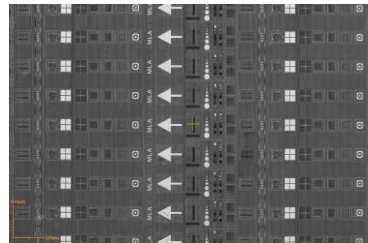
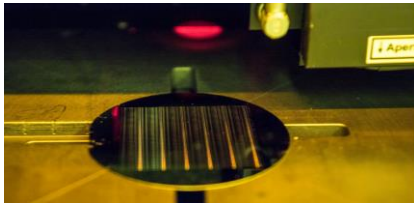
- Photolithography (UV photons)

- Shine light through a mask

MJB4 aligner



- Maskless photolithography (direct writing on wafers)



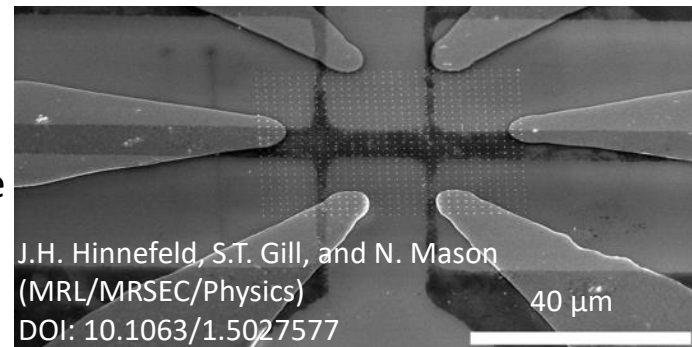
Heidelberg MLA150

- E-beam lithography (electrons)

Already have: Raith eLine

Coming soon: Raith EBPG 100 kV

Raith eLine



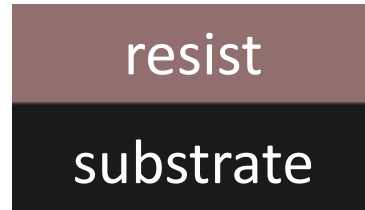
J.H. Hinnefeld, S.T. Gill, and N. Mason
(MRL/MRSEC/Physics)

DOI: 10.1063/1.5027577

40 μm

Lithography

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2. Expose a pattern; develop (remove) resist



3. Deposit material (gold, etc.)

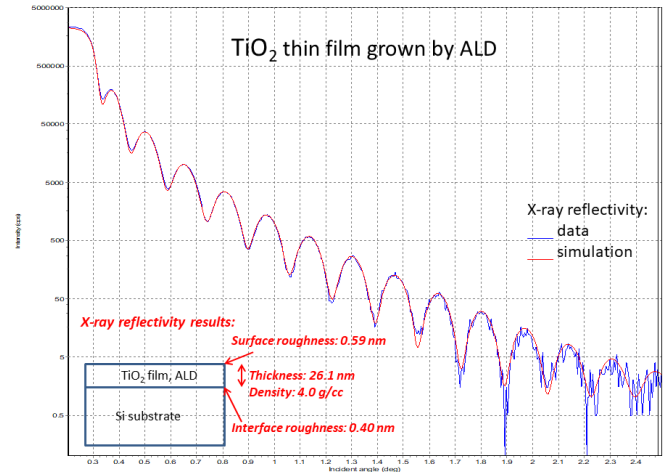


4. Liftoff (remove remaining resist)

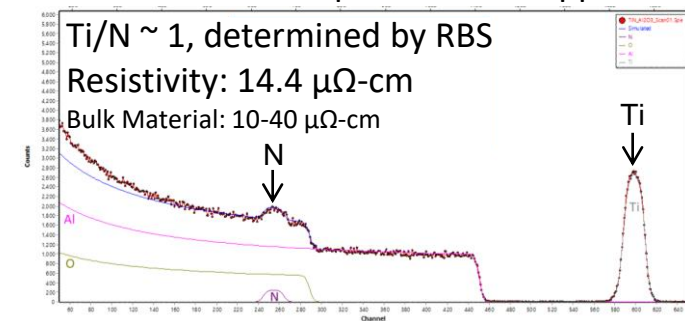


Thin Film Deposition

- Metals, oxides, nitrides, etc.
- Atomic Layer Deposition
- Magnetron Sputtering
- Thermal Evaporation
- E-beam Evaporation
- 2D Nanomaterial Growth
- Parylene Coating

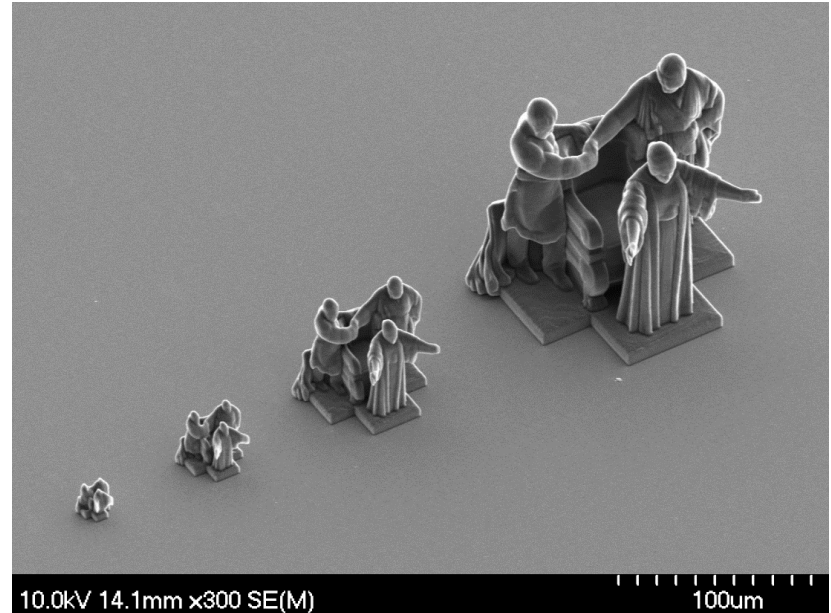


Titanium Nitride sputtered on Sapphire



Nanoscale 3D Printing

- Feature sizes down to 250 nm
- 200 μm x 200 μm field of view for high resolution
- 400 μm x 400 μm FOV or stitching possible
- Photoresist
- Write on silicon wafers, fused silica, quartz, or sapphire



Fabricated using the Nanoscribe GT
Imaged using the Hitachi S4800 SEM

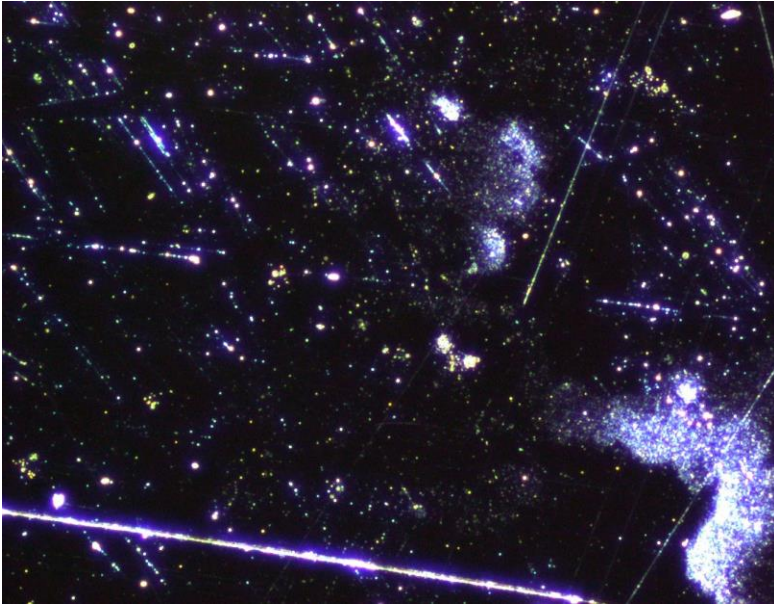
Materials Characterization

- What does it look like?
- What is it made of?
- How does it behave?

What Does It Look Like?

- Optical Microscopies
- Scanning Electron Microscopy
- Transmission Electron Microscopy
- Atomic Force Microscopy

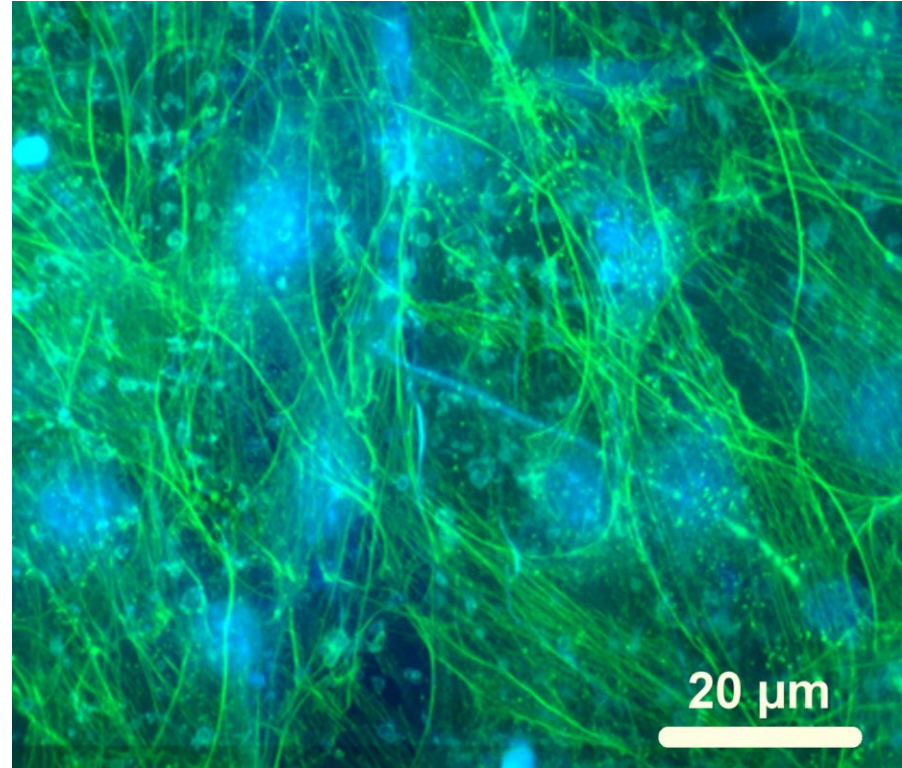
Optical Microscopies



steel hardness calibration standard
(dark field)



bug head
(bright field)

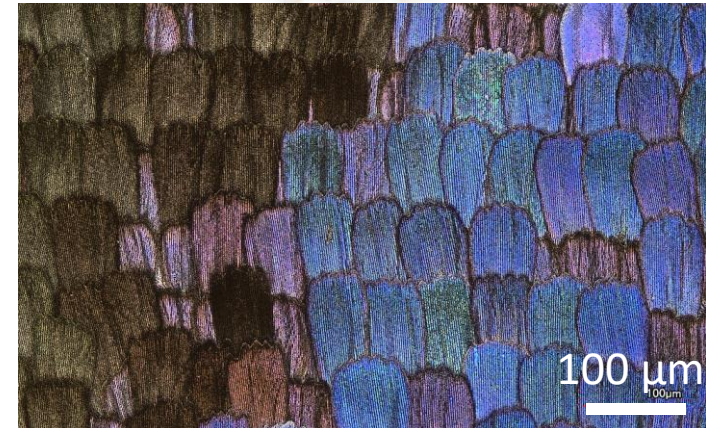


fibroblasts network on epoxy
confocal fluorescence image, courtesy of
Joselle McCracken (Nuzzo Group)

Optical Microscopies

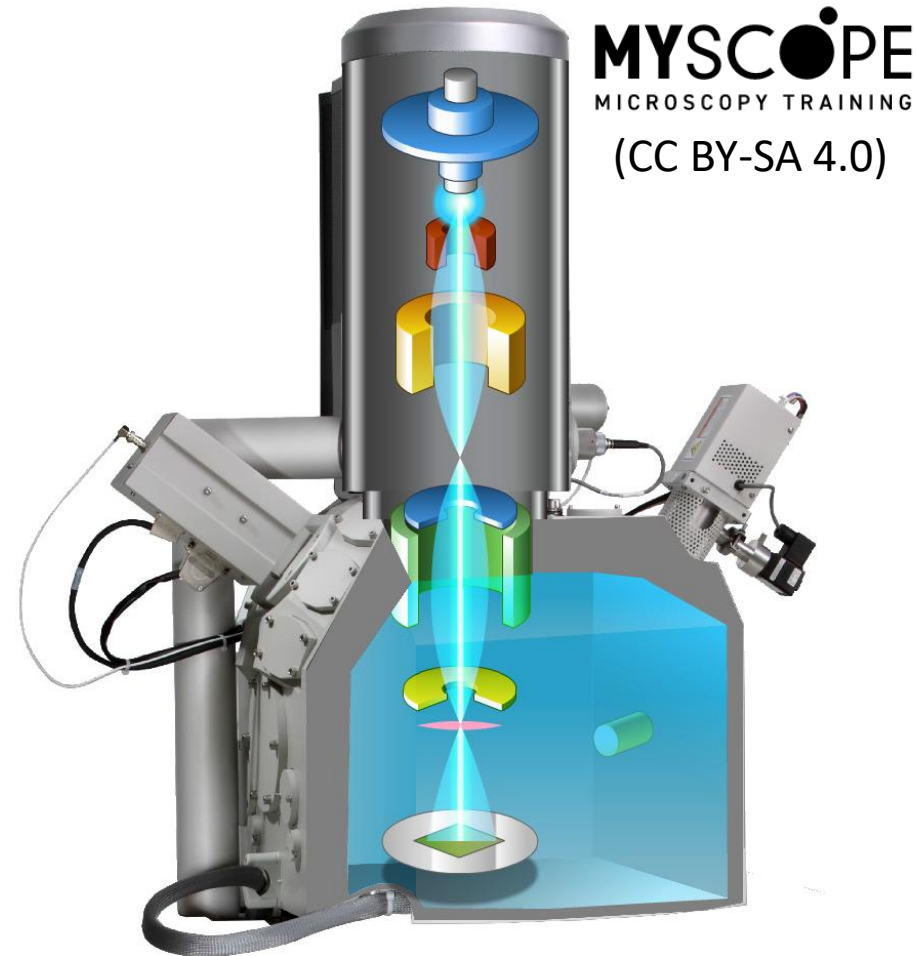
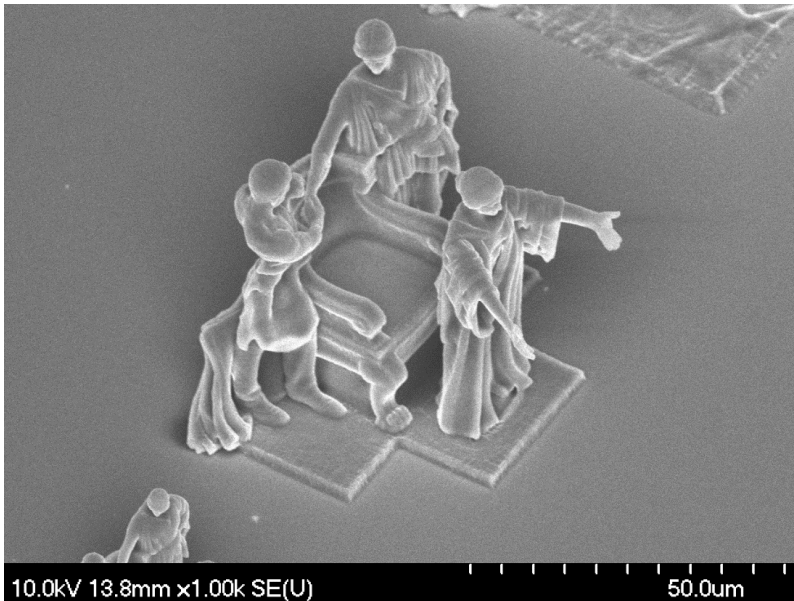
- Ordinary optical microscopy, fluorescent tagging
- Optical sectioning
- Resolution limited by wavelength ($\lambda/2$)

ladybug imaged during Cena y Ciencias using the Keyence VK-X1000
image by Kathy Walsh, MRL Facilities
sample courtesy of Julio Soares, MRL Facilities

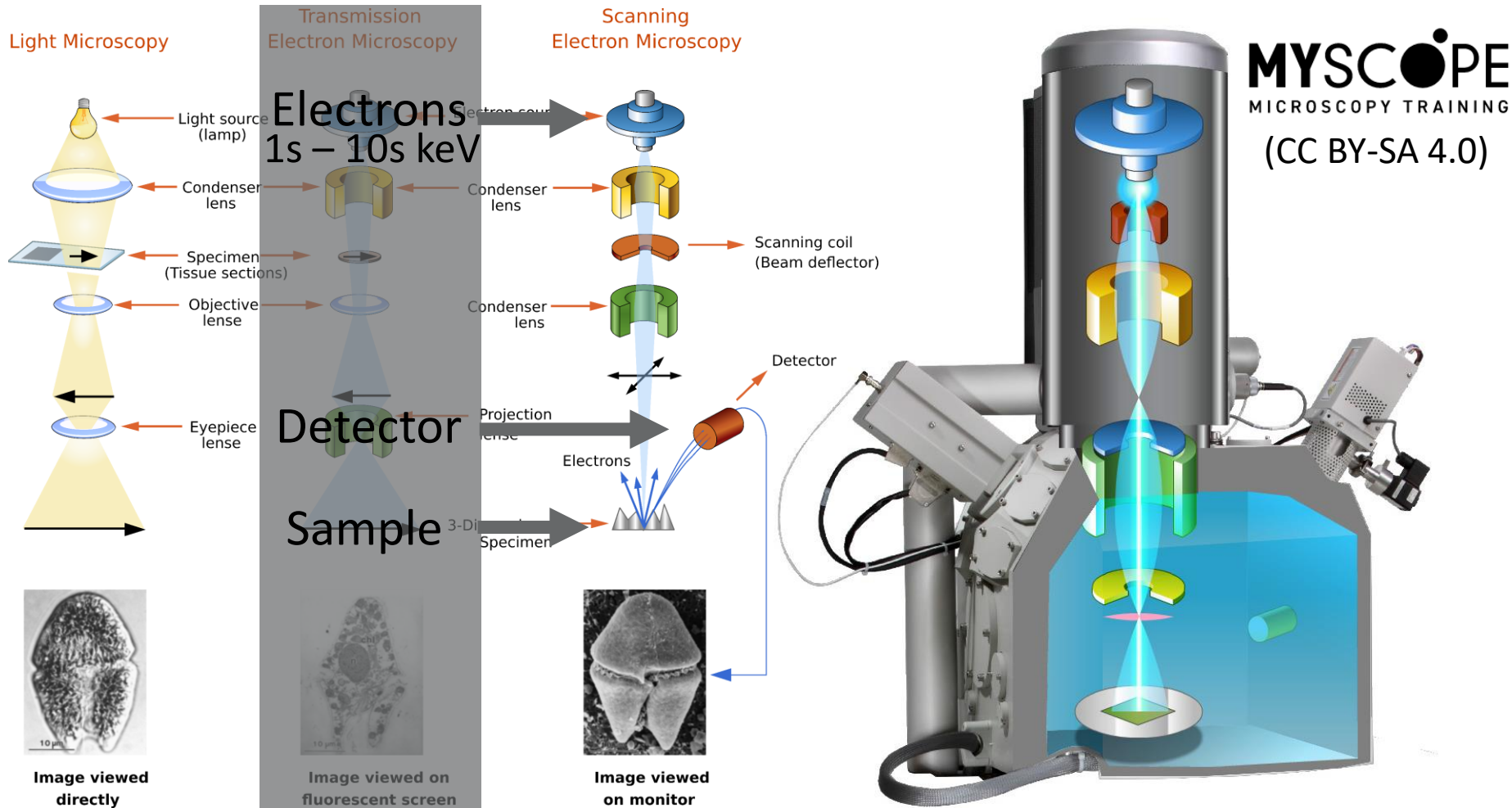


Scanning Electron Microscopy

Scan a beam of electrons back and forth across a sample surface



Scanning Electron Microscopy



https://myscope.training/#/M101level_2_6

https://myscope.training/#/SEMlevel_3_1

Scanning Electron Microscopy

More details next Monday:

Introduction to
Scanning Electron Microscopy

Monday, **April 27th, 11am** central

Dr. Honghui Zhou

MRL Senior Research Scientist

go.illinois.edu/MRLbig4webinars

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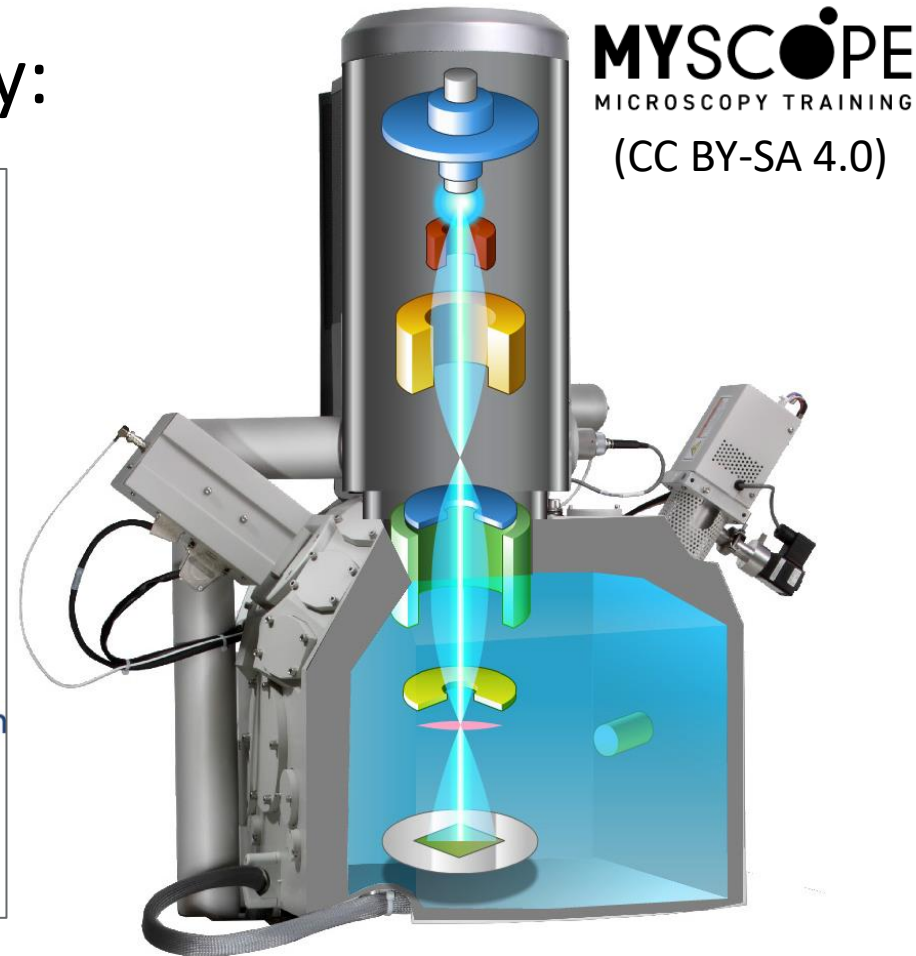


 **PennState**
Materials Research
Institute



UNIVERSITY OF MINNESOTA

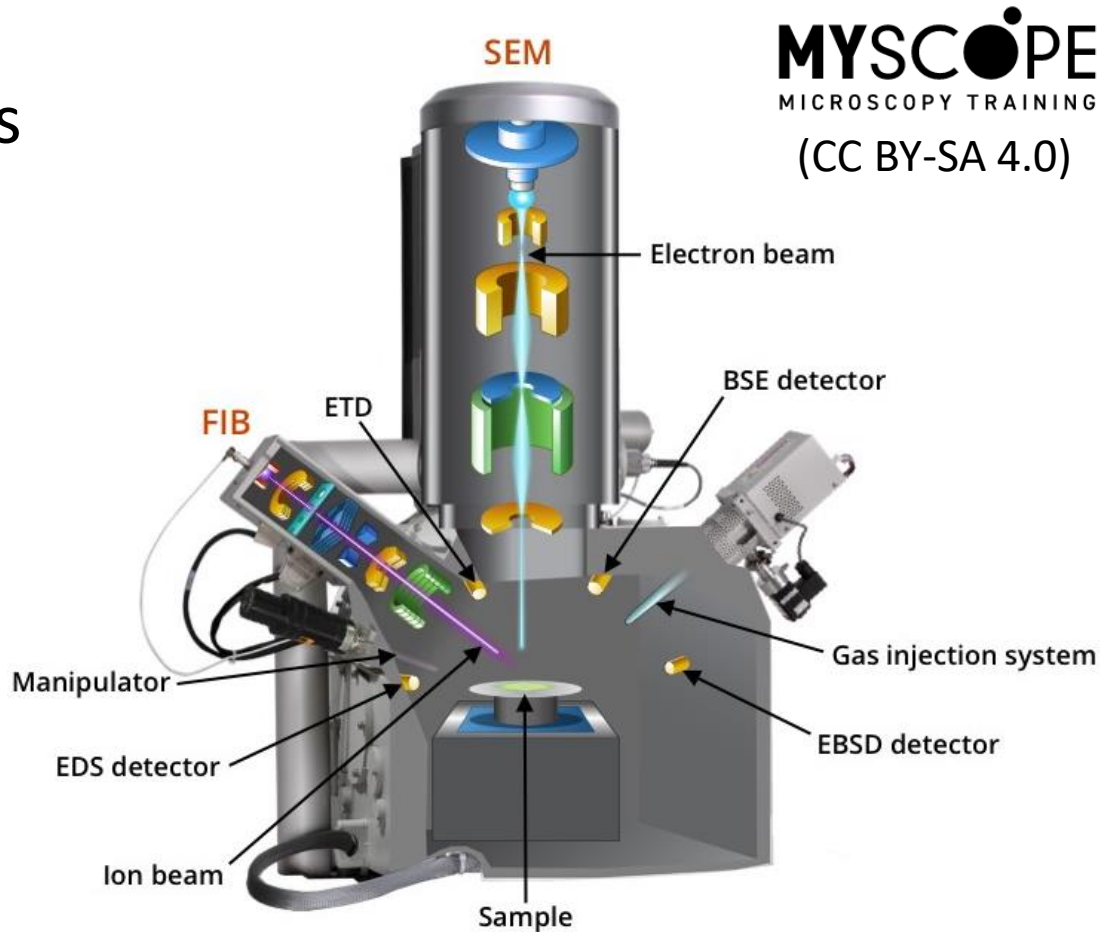
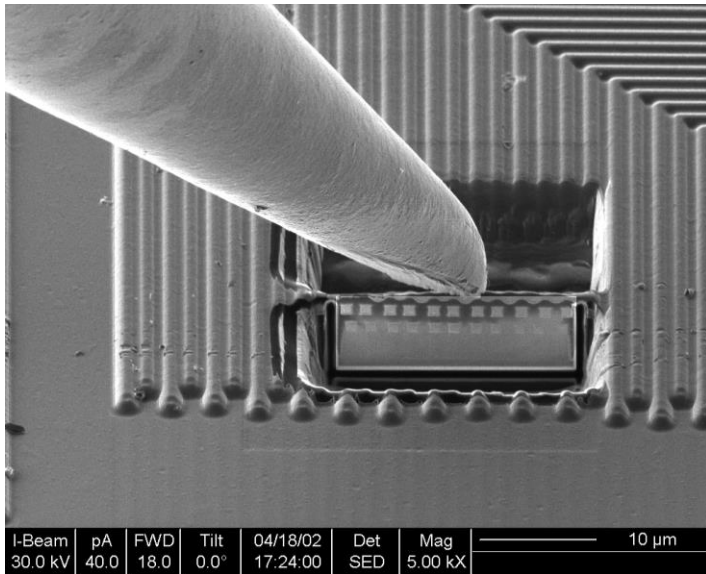
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https://myscope.training/#/SEMlevel_3_1

Focused Ion Beam

- Add a column of ions
- Lay down material
- Cut or mill sample



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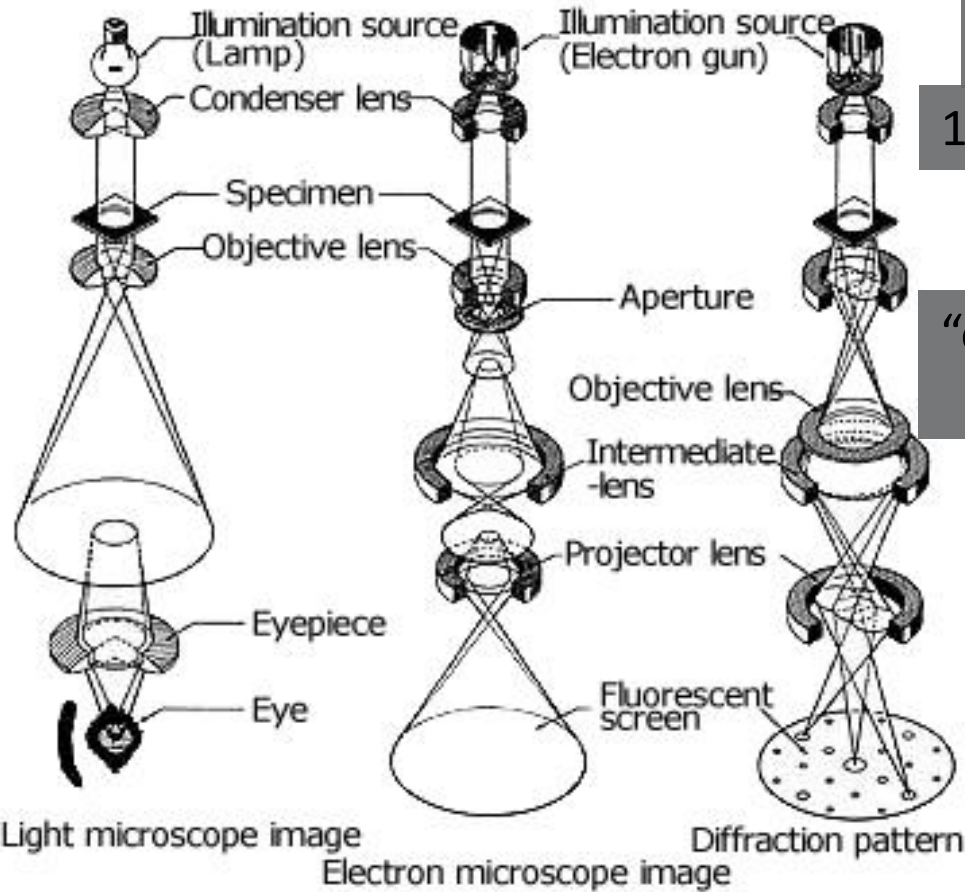
TEM Sample Preparation of Computer Chip
Using Liftout Technique
Michael Marshall, CMM

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https://myscope.training/#/FIBlevel_3_3

Transmission Electron Microscopy

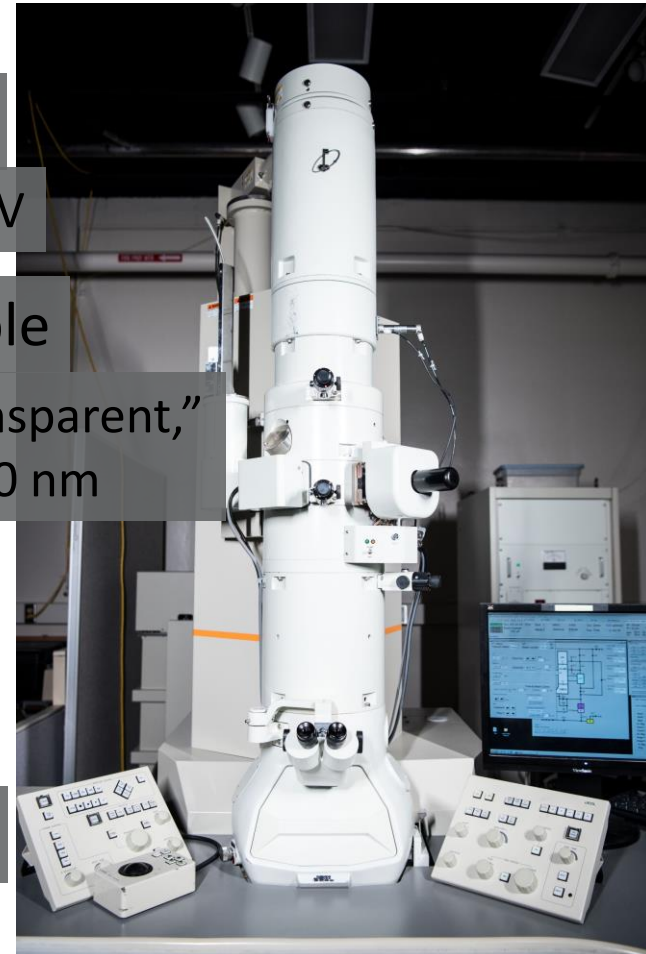
<https://www.jeol.co.jp/en/science/em.html>



Electrons
10s – 100s keV

Sample
“electron transparent,”
i.e., < 100 nm

Detector



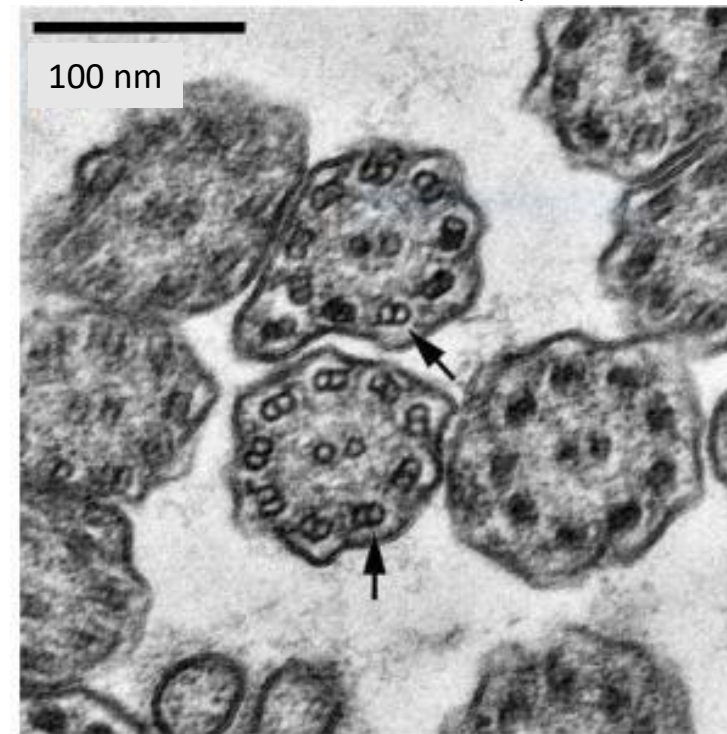
MRL's JEOL 2100 Cryo TEM

diagram from JEOL
(electron microscope manufacturer)

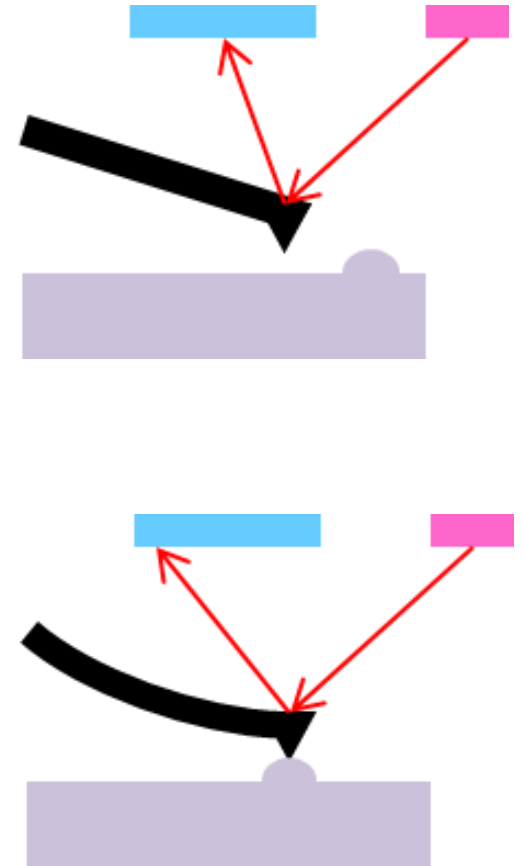
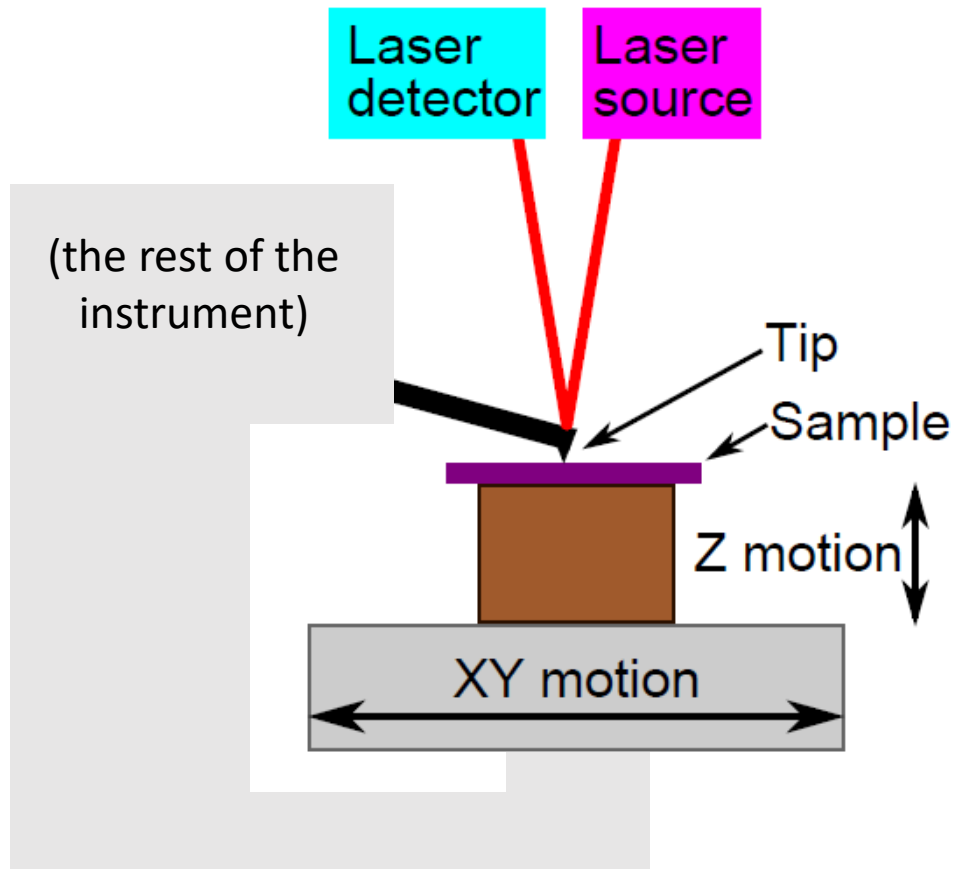
Transmission Electron Microscopy

Ultrathin sections of a canine nasal biopsy imaged under standard conditions (200kV). Arrows highlight microtubules inside the cilia.

–Kristen Flatt, MRL staff

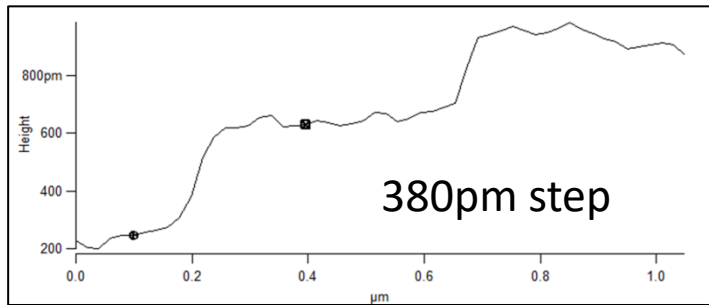
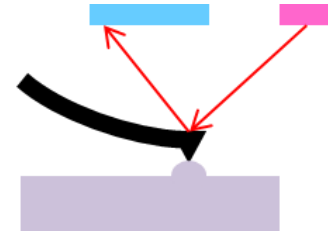


Atomic Force Microscopy

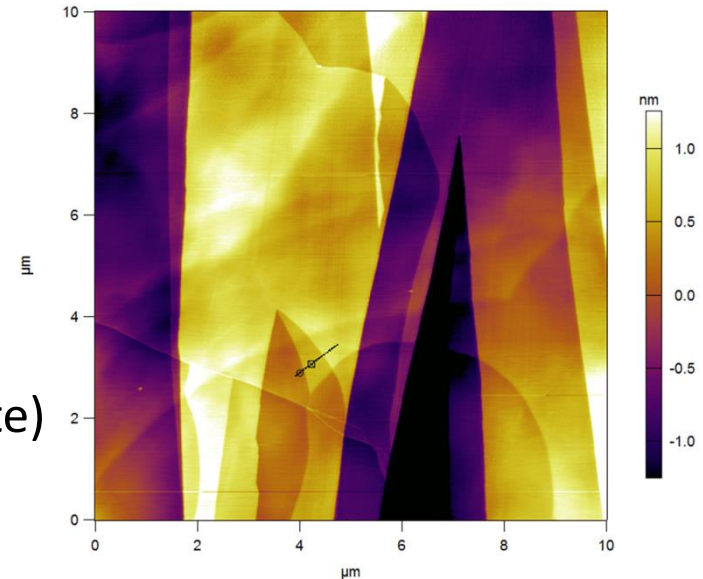


Atomic Force Microscopy

“Basics of Atomic Force Microscopy” webinar
mediaspace.illinois.edu/channel/MRL_Webinars



HOPG (highly oriented pyrolytic graphite)



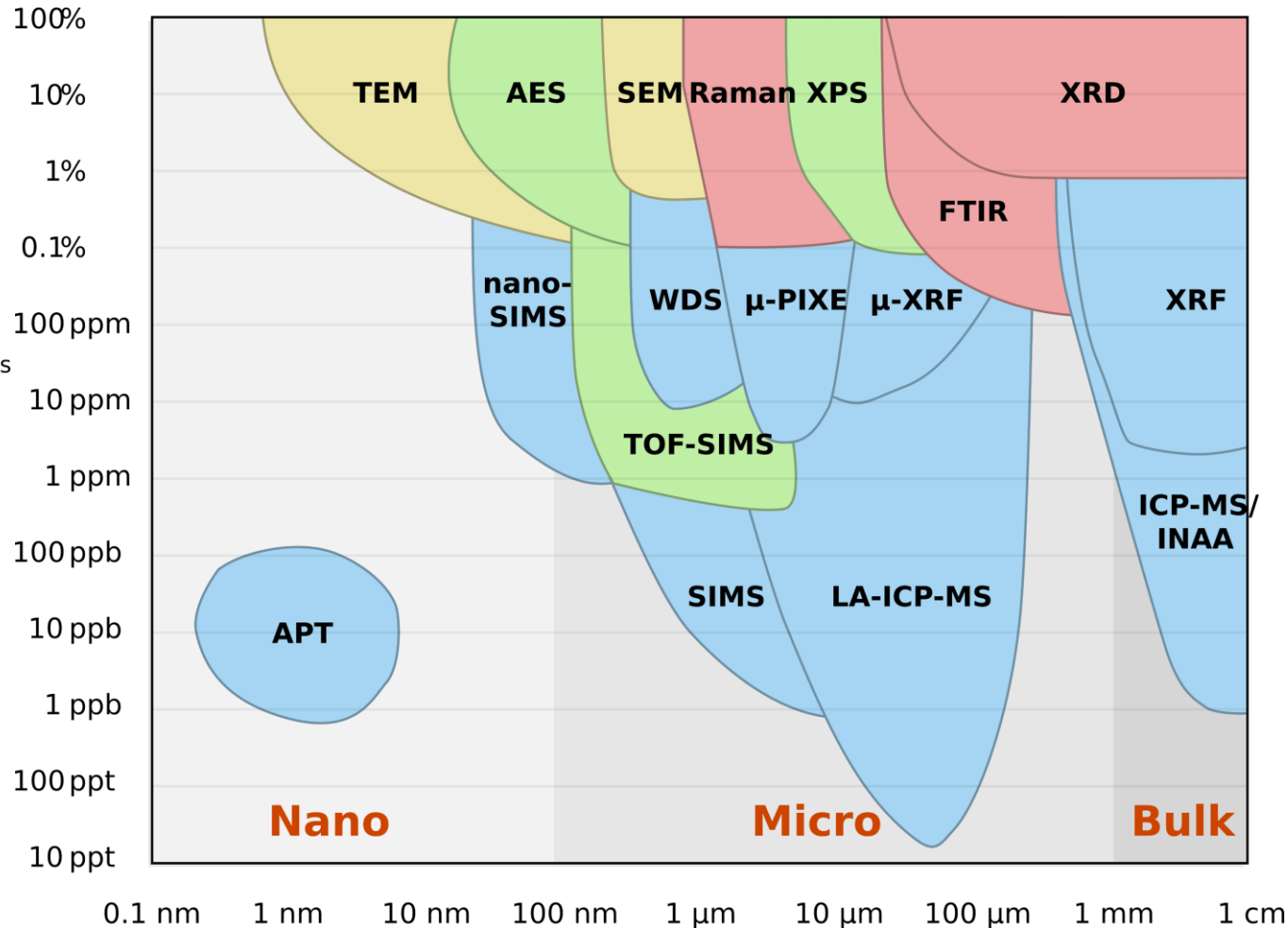
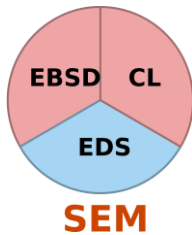
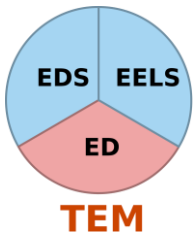
What Is It Made Of?

- Surface Analysis
 - X-ray photoelectron spectroscopy
 - Secondary ion mass spectroscopy
 - Atom probe tomography
- Raman spectroscopy
- X-ray analysis
 - Energy dispersive spectroscopy/X-ray fluorescence
 - X-ray diffraction
 - X-ray reflectivity

Compositional Analysis

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- Elemental composition
- Structural information
- Surface and thin film analysis
- SEM and TEM host multiple techniques

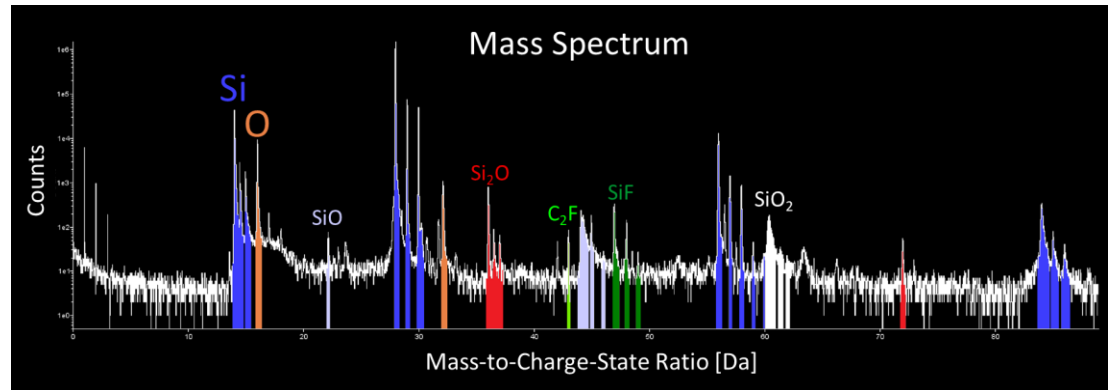


Surface Analysis

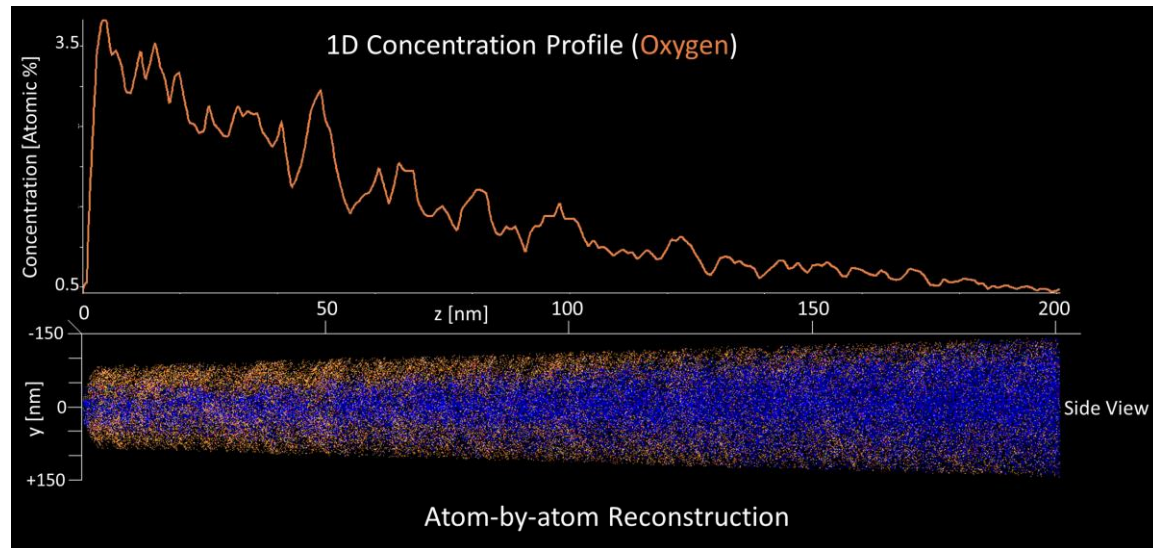
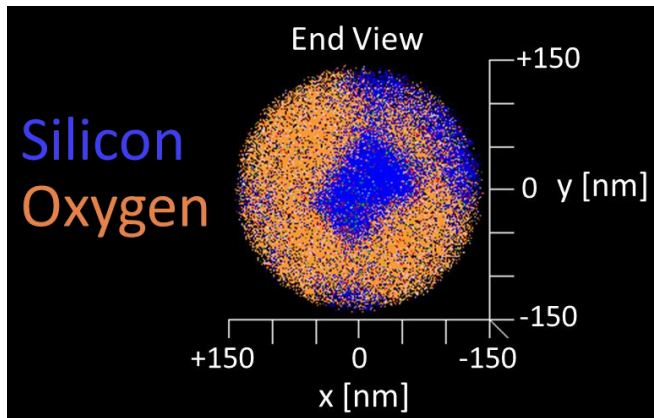
- XPS (X-ray photoelectron spectroscopy)
 - **April 23rd**, noon, go.illinois.edu/MRLwebinars
 - X-rays hit sample, knock electrons out
 - Top 10 nm of sample, ~ 1 mm analysis area
 - Chemical information and binding states
- SIMS (secondary ion mass spectrometry)
 - **April 30th**, noon, go.illinois.edu/MRLwebinars
 - Ions sputtered from sample, mass spec identifies atoms and molecules

Atom Probe Tomography

go.illinois.edu/AtomProbe

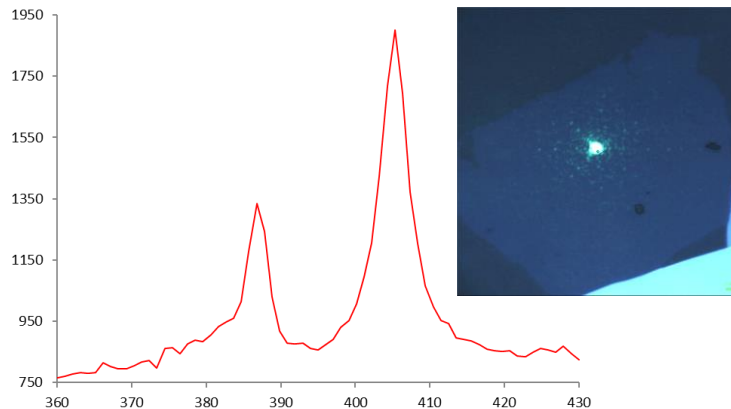


silicon microtip with oxide layer



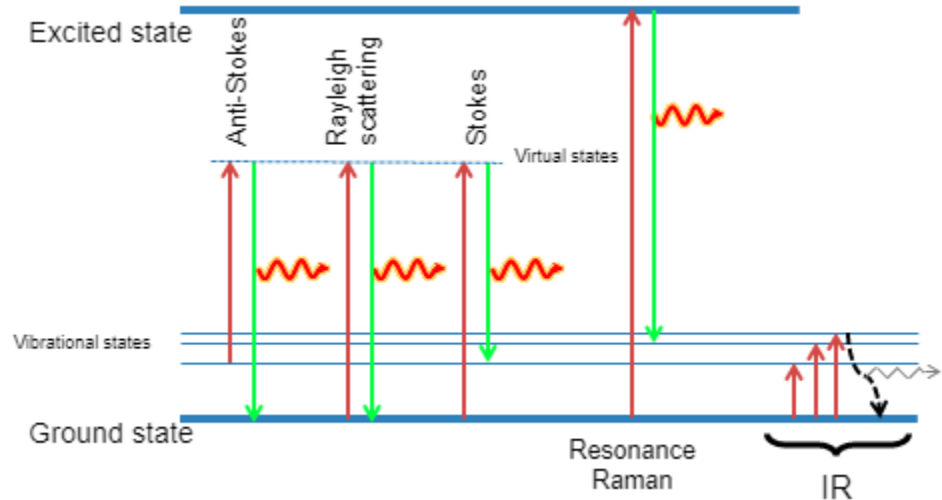
Raman Spectroscopy

- Inelastic light scattering
- Laser excites phonons, molecular vibrations



Confocal Raman on MoS₂

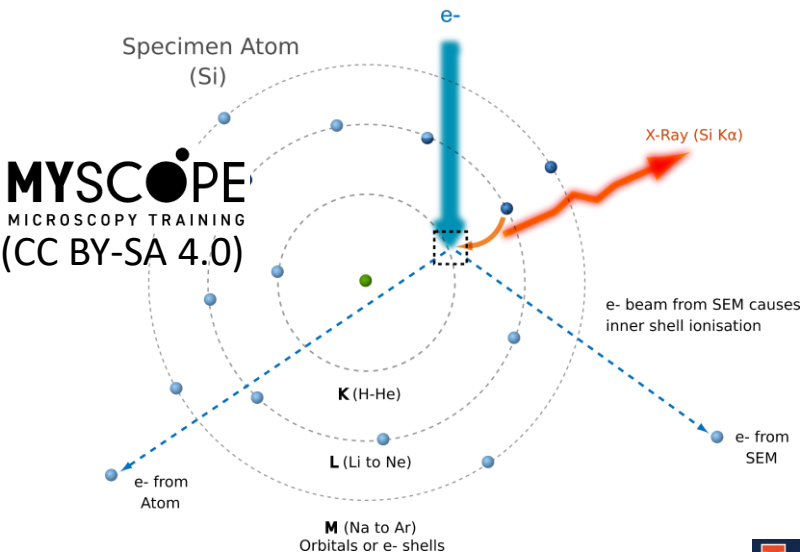
data courtesy of Mike Wang (formerly Nam Group, now professor at University of South Florida)



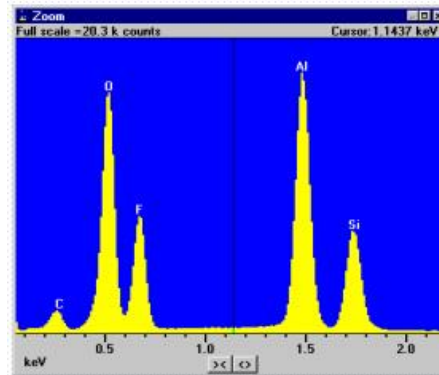
X-Ray Compositional Analysis

- Characteristic X-rays
- Analytical SEM (EDS)
- X-ray fluorescence

Characteristic X-Ray Production



Point (area) analysis

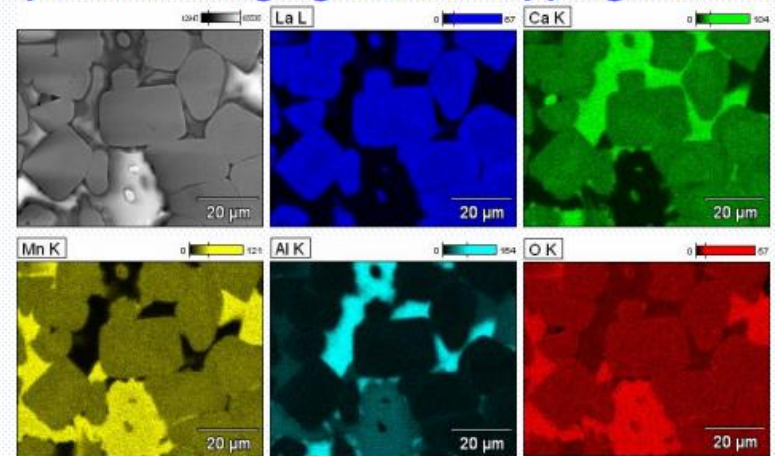


Quantification

Elmt	Spect. Type	Inten. Corr.	Std Corr.	Element %	Sigma %
Mg K	ED	0.857	1.13	6.27	0.12
Al K	ED	0.872	1.32	11.24	0.14
Si K	ED	0.855	1.57	18.49	0.15
Ca K	ED	1.003	1.47	3.05	0.08
Mn K	ED	0.825	1.21	0.95	0.10
Fe K	ED	0.838	1.15	16.85	0.22
O				43.75	0.23
Total				100.00	

* = <2 Sigma

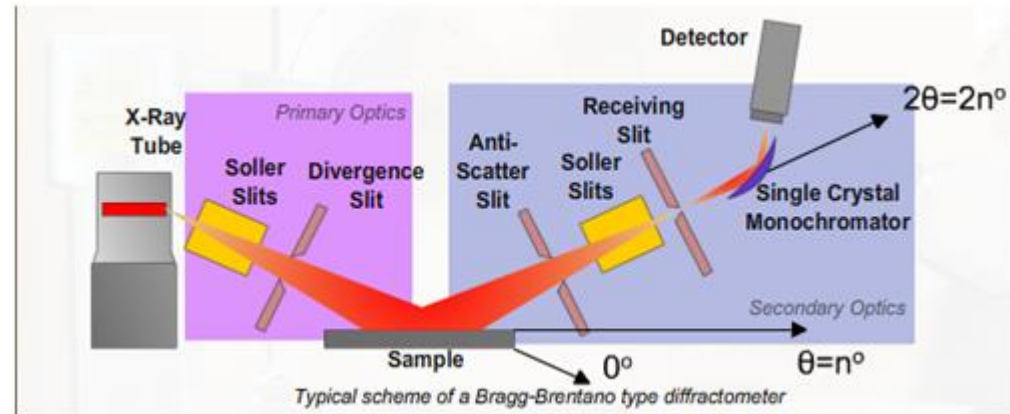
Spectrum Imaging – Area Mapping, Line Scan



https://myscope.training/#/EDSlevel_2_9

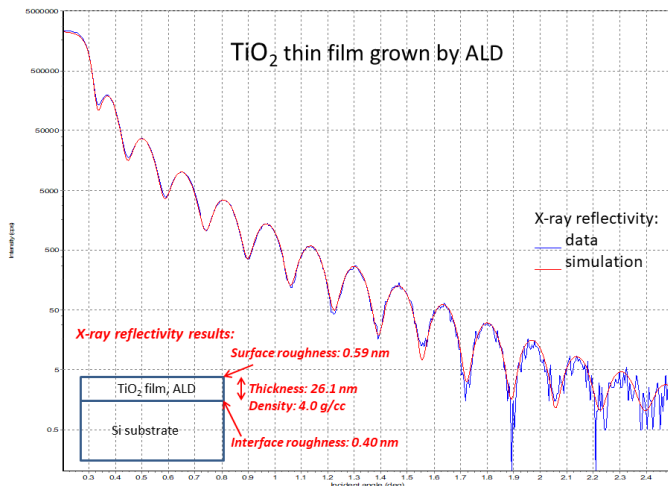
X-Ray Characterization

- X-ray diffraction
 - Crystallinity
 - Composition
- X-ray reflectivity
 - Film thickness
 - Roughness of buried interfaces



<https://myscope.training/legacy/xrd/background/whatisxrd/>

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How Does It Behave?

- Mechanical characterization
 - Dynamic mechanical analyzer (bending, pulling)
 - Rheometer (twisting)
 - Nanomechanical analysis (nanoscale compression)
- PPMS/MPMS
- Electrical characterization
 - 4-point probe/sheet resistance
 - Cryogenic probe station
 - Conductive AFM



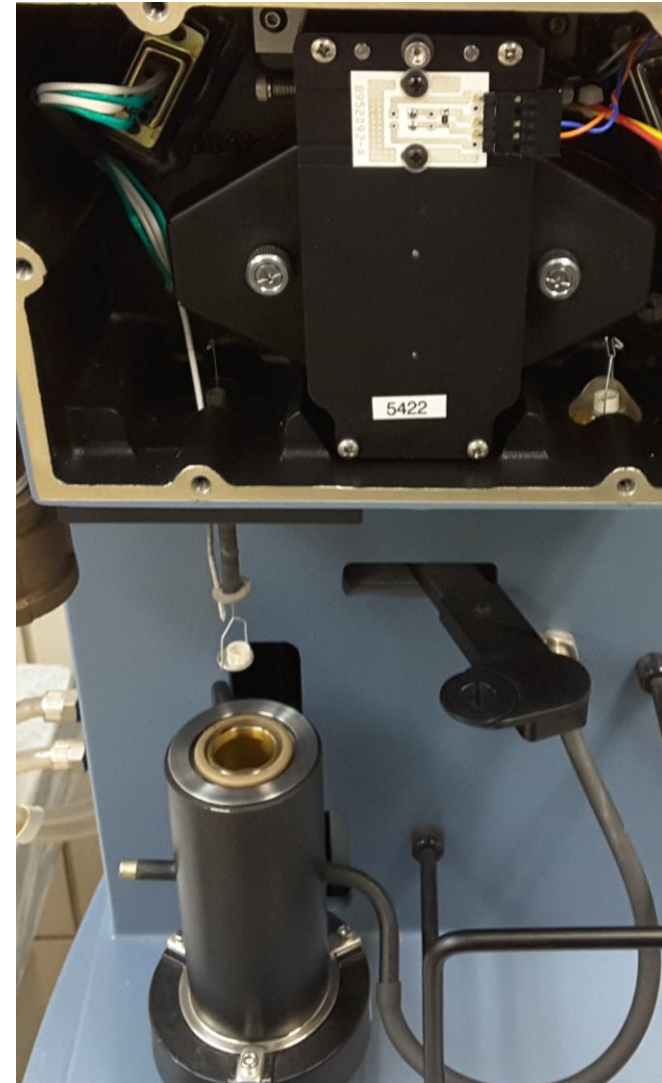
Thermal Analysis

“Soft Materials Characterization: An Instrument Overview”

- mediaspace.illinois.edu/channel/MRL_Webinars
- “basics of chromatography, thermal and mechanical analyses, as well as a sprinkling of elastic light scattering, as they relate to soft materials research”

Thermogravimetric Analysis

- Glass transition temperature and other phase transitions
- Oxidation, decomposition, thermal stability



MRL Webinar Series

go.illinois.edu/MRLwebinars

Thursdays at noon central time

Date	Title
April 2 (recording available)	Basics of atomic force microscopy
April 9 (recording available)	Soft materials characterization: An instrument overview
April 16 (recording available)	Advanced scanning electron microscopy – What is available at MRL?
April 23	Introduction to X-ray photoelectron spectroscopy (XPS)
April 30	Introduction to secondary ion mass spectrometry (SIMS)
May 7	3D optical profilometry
May 14	Practical microanalysis based on scanning electron microscopy

mrl.illinois.edu/facilities



mrl-facilities@illinois.edu
Kathy Walsh, kawalsh@illinois.edu

Resources

- **go.illinois.edu/MRLwebinars**
 - Introduction to XPS 4/23, Introduction to SIMS 4/30 (noon)
 - mediaspace.illinois.edu/channel/MRL_Webinars
- **go.illinois.edu/MRLbig4webinars**
 - Introduction to Scanning Electron Microscopy 4/27 (11am)
- <https://myscope.training>

- mrl.illinois.edu/facilities
- mrl-facilities@illinois.edu
- kawalsh@illinois.edu

submit proposal → be trained
→ do science

go.illinois.edu/MRLorientation